

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Application of: Latchford, et al.

Serial No.:

09/921,938

Confirmation No.: 8367

Filed: August 2, 2001

Photolithography Scheme Using a

Silicon Containing Resist

Box AF

**Assistant Commissioner for Patents** 

Washington, D.C. 20231

**Group Art Unit:** 

1752

Examiner:

A. C. Walke

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on October 7, 2002 with the United States Postal Service as First Class Mail in an envelope addressed to: Box AF Commissioner for Patents, Washington, D.C. 20231.

Dear Sir:

## PETITION FOR TWO-MONTH EXTENSION OF TIME

Applicant respectfully petitions the Commissioner under 37 CFR 1.136(a) to grant a two-month extension of time to and including October 7, 2002, in which to file the Notice of Appeal.

This form is filed in duplicate. The Commissioner is authorized to charge the fee of \$290.00 for the two month extension (following a prior one-month extension) and any additional fees which may be required for this submission to Deposit Account No. 20-0782/AMAT/4227.P1/DSM/BCVD/KMT.

Respectfully submitted,

Keith M. Tackett

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